Docket No.: ASMJP.137AUS

September 30, 2005 Page 1 of 1

OCT 0 3 2005 W

Please Direct All Correspondence to Customer Number 20995

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

HYODO, et al.

App. No

10/644,195

Filed

: August 20, 2003

For

METHOD OF FORMING SILICON-

CONTAINING INSULATION FILM

HAVING LOW DIELECTRIC CONSTANT AND LOW FILM

STRESS

Examiner

Huynh, Yennhu B

Art Unit

2813

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

September 30, 2005

(Date)

Katsuhiro Arai, Reg. No. 43,315

STATUS LETTER

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Upon review of our records and any available PAIR record, it appears there has been no action in the above-referenced application since Response to Restriction Requirement was filed on February 7, 2005.

Please inform us as to the status of this application.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: September 30, 2005

Katsuhiro Arai

Registration No. 43,315

Attorney of Record

Customer No. 20,995

(949) 760-0404

1962346 092905 By: